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Table of Contents

Preface iii

Chapter 1 Multiple Gates

| | |
|---|----|
| Multiple Gates for SOI MOSFETs : Two, Three or Four? * <i>S. Cristoloveanu</i> | 3 |
| Triple Gate FinFET Parameter Extraction Using High Frequency Capacitance - Voltage Curves <i>M. Rodrigues, V. Sonnenberg and J. A. Martino</i> | 9 |
| Low Temperature Operation of Undoped Body Triple-Gate FinFETs from an Analog Perspective <i>M. A. Pavanello, J. A. Martino, E. Simoen, R. Rooyackers, N. Collaert and C. Claeys</i> | 19 |
| Influence of the N-Type FinFET Width on the Zero Temperature Coefficient <i>M. Bellodi, J. A. Martino, L. M. Camillo, E. Simoen and C. Claeys</i> | 29 |
| Sidewall Angle Influence on the FinFET Analog Parameters <i>R. Giacomini, J. A. Martino and M. A. Pavanello</i> | 37 |
| Improved Compact Model for Symmetric Doped Double-Gate MOSFETs <i>A. Cerdeira, B. Iniguez and M. Estrada</i> | 47 |
| The Coherent FinFET <i>C. R. Da Cunha</i> | 57 |
| Distortion Analysis of Triple-Gate Transistor in Saturation <i>J. E. Conde, A. Cereira and M. Estrada</i> | 67 |
| On the Threshold Voltage of Undoped Double-Gate SOI MOSFETs <i>F. J. Garcia-Sanchez, A. Ortiz-Conde, J. Muci and R. Salazar</i> | 75 |

Chapter 2 Thin Films and Processes

| | |
|---|-----|
| Semiconductor Surface Cleaning and Conditioning Challenges Beyond Planar Silicon Technology * | 87 |
| <i>J. Ruzyllo</i> | |
| Advanced ESD Protection Solutions in CMOS/BiCMOS Technologies * | 97 |
| <i>J. J. Liou, J. A. Salcedo and Z. Liu</i> | |
| Ultra-Thin Deformable Silicon Substrates with Lateral Segmentation and Flexible Metal Interconnect | 103 |
| <i>T. Zoumpoulidis, L. Wang, M. Bartek, K. Jansen and L. J. Ernst</i> | |
| Stress Analysis on Ultra Thin Ground Wafers | 113 |
| <i>R. C. Teixeira, K. De Munck, P. De Moor, K. Baert, B. Swinnen, C. Van Hoof and A. Kuttel</i> | |
| Anisotropic Resistivity of PMMA Doped with Gold | 123 |
| <i>F. S. Teixeira, R. D. Mansano, M. C. Salvadori, M. Cattani and I. G. Brown</i> | |
| A Gravimetric Technique to Determine the Crystallite Size Distribution in High Porosity Nanoporous Silicon | 133 |
| <i>M. du Plessis</i> | |
| The Effect of Si-Substrate on the Optical Characterization of Ge Nanostructures Obtained by LPCVD | 143 |
| <i>S. N. Mestanza, E. Rodriguez, I. Doi, A. R. Vaz and N. C. Frateschi</i> | |
| Dynamic Scaling of the Surface Roughness During Electroless Cu Plating onto Si in Aqueous Fluoride Solution | 151 |
| <i>G. Gozzi and G. dos Santos Flho</i> | |
| ECR-CVD SiNX Passivation in GaAs-based MISFET Devices | 159 |
| <i>L. B. Zoccal, J. A. Diniz, J. G. Fo, A. Daltrini and J. W. Swart</i> | |
| GaAs and AlGaAs reactive ion etching in SiCl ₄ /Ar gas mixtures for HEMT applications | 169 |
| <i>A. M. Nunes, S. A. Moshkalev, P. J. Tatsch, C. A. Duarte and G. M. Gusev</i> | |
| Design of Finish Process of Freeform Surface in Magnetic-Assistance Electrochemical Finishing | 179 |
| <i>P. S. Pa</i> | |

| | |
|--|-----|
| Effect of the Substrate Heating Due to the Sputtering Process on the Crystallinity of TiO ₂ Thin Films <i>H. Toku, R. S. Pessoa, T. B. Liberato, M. Massi, H. S. Maciel and A. S. da Silva Sobrinho</i> | 189 |
| Electroless Deposition of CuNiP Alloys onto Silicon Surfaces <i>F. T. Parra, S. G. dos Santos Filho, A. E. Marques and S. Martini</i> | 199 |
| Improvement of Polymeric Electroluminescent Device Structures Through Simulation of UV-Vis Absorption Spectra of PANI/PVS Films <i>J. P. Lima and A. M. de Andrade</i> | 207 |
| Contact Improvement for Carbon Nanotubes Deposited by Dielectrophoresis <i>J. Leon, A. R. Vaz, A. Flacker, S. A. Moshkalev, M. B. de Moraes and J. W. Swart</i> | 213 |
| The Influence of Substrates on the Carbon Nanotube Growth Process <i>M. R. de Aguiar, C. Verissimo, S. A. Moshkalev and J. W. Swart</i> | 219 |
| Etching Studies of Post-Annealed SiC Films Deposited by PECVD: Influence of the Oxygen Concentration <i>M. A. Fraga, R. S. Pessoa, M. Massi, H. S. Maciel and S. G. dos Santos Filho</i> | 227 |
| Electrical Characterization of Platinum Thin Films Deposited by Focused Ion Beam <i>M. M. da Silva, A. R. Vaz, S. A. Moshkalev and J. W. Swart</i> | 235 |
| Novel Europium β -diketonate Complex in Organic Light Emitting Diode: Eu(BTA) ₃ bipy [tris(1-(2-benzoyl)-3,3,3-trifluoroacetone)-bipyridine, Europium(III)] <i>G. Santos, F. J. Fonseca, A. M. Andrade, S. S. Braga, A. C. Coelho, I. S. Goncalves, W. Simoes and L. Pereira</i> | 243 |
| Deposition and Characterization of Indium-Tin Oxide Thin Films Deposited by RF Sputtering <i>L. R. Damiani and R. D. Mansano</i> | 251 |
| Electrical Characterization of a-C:H as Insulator Material in MIM Structures <i>C. Zuniga-I, A. I. Kosarev, A. Torres-J, C. Reyes-Betanzo, W. Calleja-A and P. Rosales</i> | 259 |
| Clusters Formation by Rapid Thermal Annealing on SiO ₂ /Ge and SiH/Ge Heterostructures <i>A. M. dos Anjos, J. A. Diniz, L. B. Zoccal, U. A. Mengui, M. A. Canesqui and I. Doi</i> | 269 |

Chapter 3 Characterization and Modeling

| | |
|---|-----|
| Physical Characterization and Reliability Aspects of MuGFETs * | 281 |
| <i>C. Claeys, E. Simoen, J. M. Rafi, M. A. Pavanello and J. A. Martino</i> | |
| Electromigration Modeling for Interconnect Structures in Microelectronics * | 295 |
| <i>H. Ceric and S. Selberherr</i> | |
| The Impact of the Gate Oxide Thickness Reduction on the Gate Induced Floating Body Effect in SOI nMOSFETs | 305 |
| <i>P. G. Der Agopian, J. A. Martino, E. Simoen and C. Claeys</i> | |
| A Study Of Flicker Noise In MOS Transistor Under Switched Bias Condition | 313 |
| <i>M. Miguez and A. Arnaud</i> | |
| Analysis of Matching in Graded-Channel SOI MOSFETs | 323 |
| <i>M. de Souza, D. Flandre and M. A. Pavanello</i> | |
| Fundamentals, Computer Implementation and Applications of the Advanced Compact MOSFET (ACM) Model | 333 |
| <i>O. F. Siebel, M. C. Schneider and C. Galup-Montoro</i> | |
| Improved Model to Determine the Generation Lifetime in Double Gate SOI nMOSFETs | 343 |
| <i>M. Galetti, J. A. Martino, E. Simoen and C. Claeys</i> | |
| Electrical Studies on Metal /SrTa2O6 or TiO2/ Si Substrate Stack Systems | 353 |
| <i>O. O. Awadelkarim, J. Jiang, S. A. Suliman, K. Sarpatwari, L. J. Passmore, D. Lee, P. Roman and J. Ruzyllo</i> | |
| Modeling Negative Differential Resistance (NDR) Devices using Radial Basis Function Neural Networks | 363 |
| <i>M. C. Banderia, J. G. Guimaraes, J. A. Duraes, L. M. Silva, A. M. Ceschin, M. J. Sales and J. C. Costa</i> | |
| The Length-Dependence of the 1/f Noise of Graded-Channel SOI nMOSFETs | 373 |
| <i>E. Simoen, C. Claeys, T. M. Chung, D. Flandre and J. Raskin</i> | |
| Reversible Electrical Characteristics in PMMA on P3HT OTFTs | 383 |
| <i>I. Mejia, M. Estrada, A. Cerdeira and B. Iniguez</i> | |
| A New Method for Polynomial Coefficient Extraction Applied to Harmonic Distortion Calculation | 389 |
| <i>A. Ortiz-Conde, F. J. Garcia-Sanchez and R. Salazar</i> | |

| | |
|---|-----|
| Study of the Drain Leakage Current Behavior in Circular Gate SOI nMOSFET Using 0.13 μ m SOI CMOS Technology at High Temperatures <i>L. M. Almeida and M. Bellodi</i> | 397 |
| 10 GHz RF Passive Components Obtained by MCM-D Technology <i>L. B. Zoccal, C. M. Cabreira, S. D. Yamamoto, R. A. Flacker, E. A. Gomes, J. A. Diniz and J. W. Swart</i> | 405 |
| Three-Dimensional (3-D) Electro-Thermal Simulation of Four-Layer Devices <i>R. Quiñtero-Romo</i> | 415 |
| Coupled Quantum Dot Cell Dynamics <i>M. F. Stella, M. V. Batistuta and J. C. da Costa</i> | 423 |
| Stability of Coupled Quantum Dot Cells at Finite Temperatures <i>M. V. Batistuta, M. F. Stella and J. C. da Costa</i> | 433 |
| Impact of Graded-Channel SOI MOSFET Application on the Performance of Cascode and Wilson Current Mirrors <i>A. A. Santos, D. Flandre and M. A. Pavanello</i> | 441 |
| Improved Charge Sheet Model for PD SOI Sub-Micron MOSFETs <i>J. Alvarado, A. Cerdeira, V. Kilchytska and D. Flandre</i> | 451 |
| Study of MOS Capacitors with Annealed TiO ₂ Gate Dielectric Layer <i>K. F. Albertin, M. A. Valle and I. Pereyra</i> | 461 |

Chapter 4 **MEMS**

| | |
|--|-----|
| Silicon Microtips with Self-Asigned Integrated Electrodes <i>A. L. Barros, A. T. Lopes and M. N. Carreno</i> | 473 |
| Silicon Microtips Arrays Fabricated by HI-PS Technique for Application in Field Emission Devices <i>M. O. Dantas, M. M. Kopelvski, E. Galeazzo, H. E. Peres and J. R. Fernandez</i> | 481 |
| Simple MEMS-based Incandescent Microlamps <i>G. Rehder, M. N. Carreno and M. I. Alayo</i> | 489 |

| | |
|---|-----|
| Simulation, Fabrication and Characterization of a Tunable Bragg Reflector Based on Silicon Oxide and Silicon Nitride Dielectric Films Deposited by PECVD <i>G. S. Martins, H. Baez and M. I. Alayo</i> | 497 |
| Microstructural and Electrical Conductivity Relationships in Alumina-Containing Yttria Stabilized Cubic Zirconia Used as a Solid Electrolyte in Solid Oxide Fuel Cells <i>S. Tekeli, A. Kayis, O. Gurdal and M. Guru</i> | 505 |
| Precision Recycle Process of ITO Removal from Color Filter Using Electrochemical Machining <i>P. S. Pa</i> | 515 |
| Effect of Number of Layers on the Optical Response of Porous Silicon Bragg's Mirrors <i>D. R. Huanca and W. J. Salcedo</i> | 525 |

Chapter 5 Sensors and Actuators

| | |
|---|-----|
| Study of Nickel Silicide as Mask for Alkaline Solutions to V-grooves Fabrication <i>A. R. Mascaro, L. C. Goncalves and N. I. Mortimoto</i> | 533 |
| Zinc-Oxide Surface Acoustic Wave Device Fabrication <i>E. J. Santos and A. M. Santos</i> | 539 |
| Influence of the Interferers in the Nitrite Detection By using Planar Electrochemical Sensors <i>F. L. Ameida and M. B. Fontes</i> | 545 |
| Photoresponse Analysis of Sensors Fabricated with Standard 2.0 μm CMOS Technology <i>D. R. Huanca, E. Rodriguez, I. Doi, J. A. Diniz, J. W. Swart and N. C. Frateschi</i> | 553 |
| A Theoretical Study of a Novel Multi-Terminal Pressure Sensor Based on the Transversal Piezoresistive Effect <i>G. Coraucci and F. Fruett</i> | 561 |
| Characterization of a Isfet Device as a pH Sensor for Application in the Industrial, Environmental and Biomedical Fields <i>R. Scaff, M. B. Fontes and S. G. dos Santos Filho</i> | 571 |

| | |
|---|-----|
| Macroporous Silicon Structure Functionalized by Methylene Blue to pH Measurements Application | 579 |
| <i>D. S. Raimundo, G. S. Cechelero, A. Acosta, F. R. Fernandez and W. J. Salcedo</i> | |
| Characterization of a P3HT- Si Heterojunction for Solar Cells Applications | 587 |
| <i>J. C. Nolasco, M. Estrada, Y. Matsumoto, L. F. Marsal and J. Pallares</i> | |
| Subject Index | 595 |
| Author Index | 597 |

** Invited Papers*